

# MNC 2022



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of Applied Physics

## ABSTRACT DEADLINE

**July 1, 2022**

**November 8-11, 2022**

JR Hotel Clement Tokushima, Tokushima, Japan

## WEB ADDRESS

mnc



<https://imnc.jp/2022/>

## PLENARY SPEAKERS

“Lithography in a Quantum World”  
Dr. Harry Levinson, HJL Lithography, USA

“Forming Three Dimensional Mesostructures and Exploiting Them in Unusual Microsystems”  
Prof. John A. Rogers, Northwestern University, USA

“Everlasting CMOS Innovation: The Future Perspectives”  
Prof. Toshiro Hiramoto, The University of Tokyo, Japan

## SCOPE

- 1: Lithography, Metrology and Related Technologies
  - 1-1: Advanced Lithography and Patterning
  - 1-2: Electron and Ion Beam Technologies
  - 1-3: Patterning Materials
- 2: Nanotechnology
  - 2-1: Nanocarbon & 2D Materials
  - 2-2: Nanodevices
  - 2-3: Nanofabrication
  - 2-4: Inorganic Nanomaterials
  - 2-5: Organic Nanomaterials
  - 2-6: NanoTool
- 3: Nanoimprint, Hybrid-NIL, Biomimetics, and Functional Surfaces
- 4: BioMEMS, Lab on a Chip, and Nanobiotechnology
- 5: Microsystem Technology and MEMS
- 6: Atomic Layer Processing (ALP)

JJAP Special Issue

to be published in June, 2023

## SYMPOSIUM

**Symp. A:** Emerging Breakthroughs in Materials, Processes and Equipment for Advanced Lithography

**Symp. B:** Frontlines of atomic layer processing researches and expectations for novel precursor materials

**Symp. C:** Micro and Nanotechnology for Detecting Bioinformation (tentative)

## REGISTRATION FEE

**Pre-Registration Deadline:**  
**October 14, 2022**

Regular : 55,000 JPY

On-site Regular : 60,000 JPY

Student : 25,000 JPY

On-site Student : 30,000 JPY

## CONFERENCE CHAIRS

### ORGANIZING CHAIR:

Masao Nagase, Tokushima Univ., Japan

### STEERING CHAIR:

Katsuhiko Nishiguchi, NTT, Japan

### PROGRAM CHAIR:

Daiyu Kondo, Fujitsu, Japan

## SECRETARIAT

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